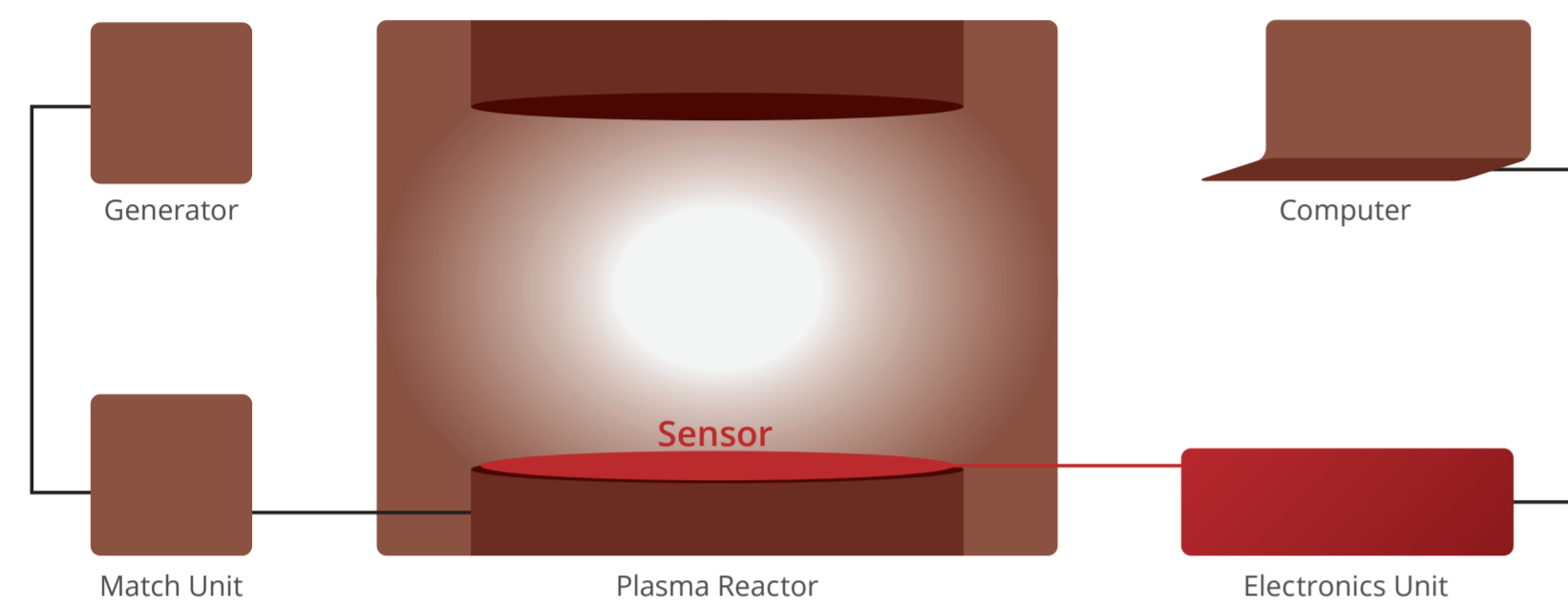


Substrate Level Ion Measurements



Semion | Vertex

Ion Energy Analyser
 Ion Energy | Ion Energy Distribution | Ion Flux
 Positive/Negative Ion | Electrode Voltage
 Ion Aspect Ratio (Vertex)

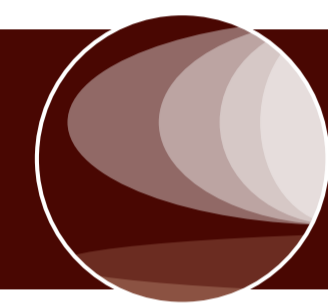
Applications
 Dusty | Etch | HiPIMS
 Ion Beam | PECVD | Space
 Sputtering



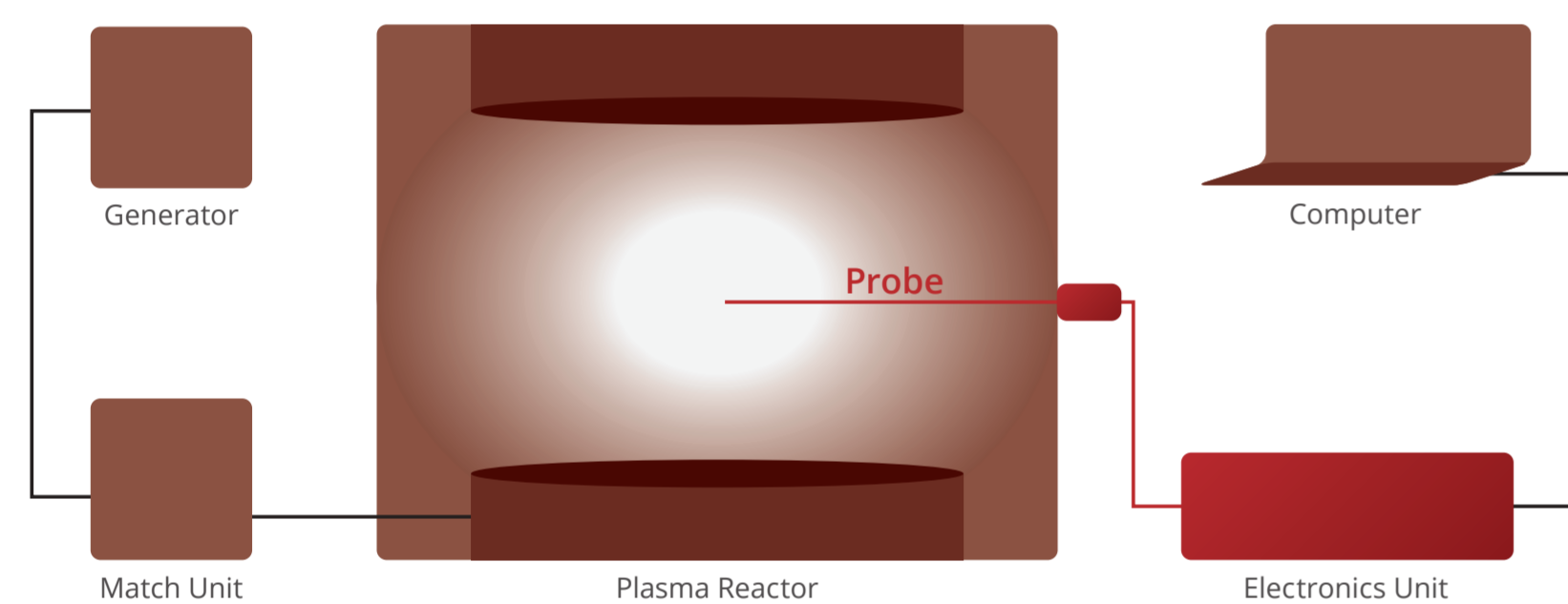
Quantum

Ion Flux Fraction
 Deposition Rate | Ion Energy
 Ion Flux
 Electrode Voltage

Applications
 Dusty | Etch | HiPIMS
 Ion Beam | PECVD | Space
 Sputtering



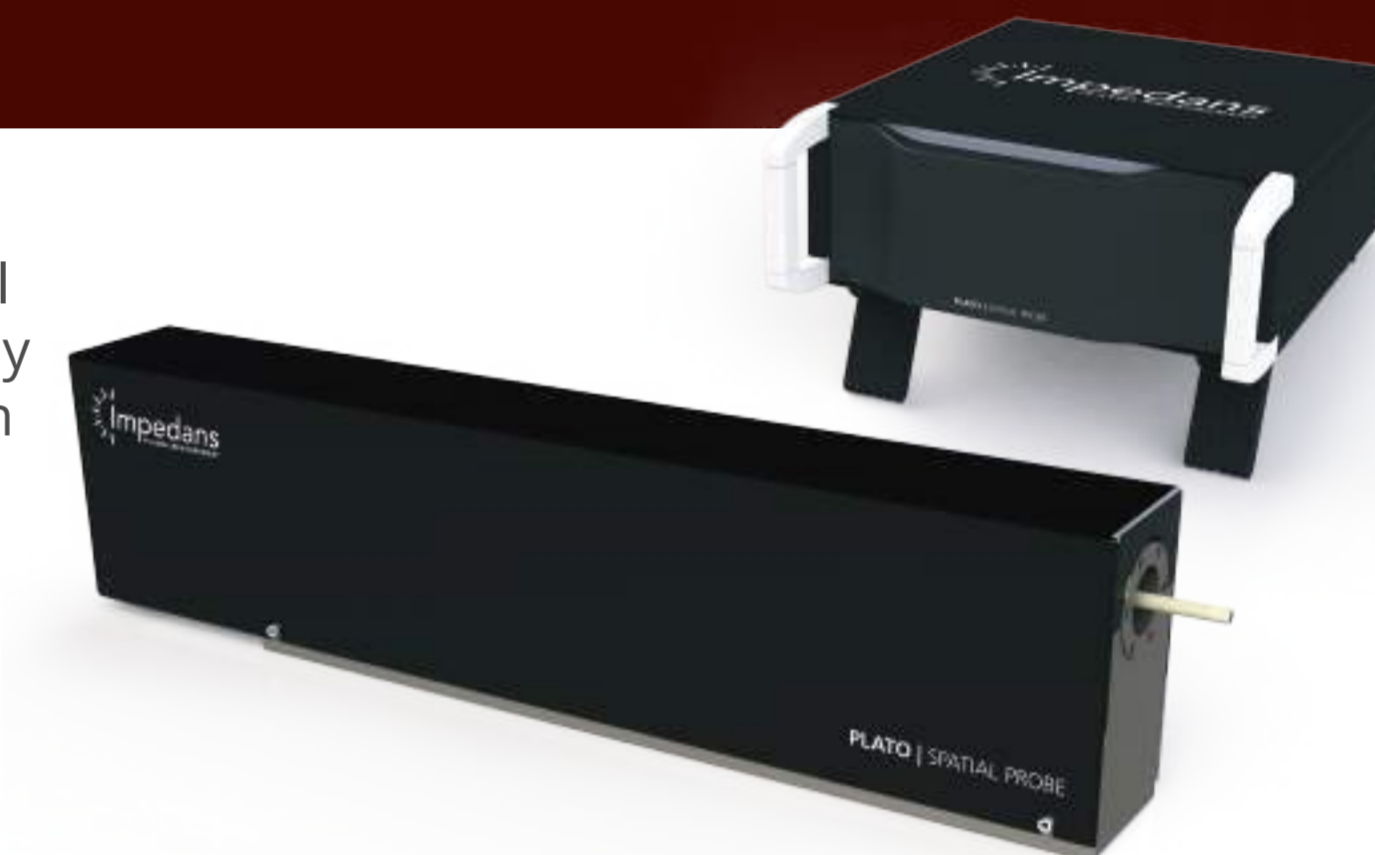
Bulk Plasma Parameter Measurements



Langmuir

Plasma Parameters
 Plasma Potential | Floating Potential
 Ion Current Density | Plasma Density
 Electron Energy Distribution Function

Applications
 Dusty | Etch | HiPIMS
 PECVD | Space | Sputtering



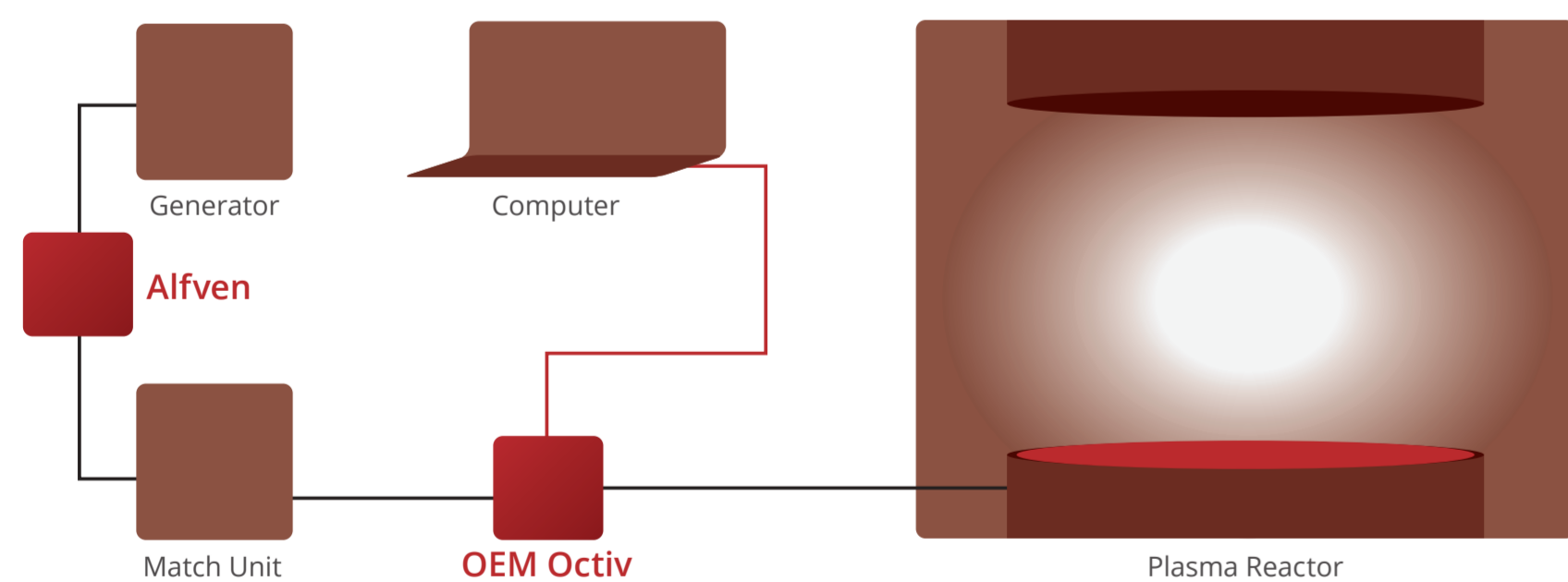
Plato

Deposition Tolerant Probe
 Plasma Density
 Ion Current Density
 Electron Temperature

Applications
 Dusty | Etch | HiPIMS
 PECVD | Space | Sputtering



Plasma Process Monitoring



Alfvén 100

Plasma Arc Detector
 Voltage | Current
 Pulse Monitoring
 Microarcs

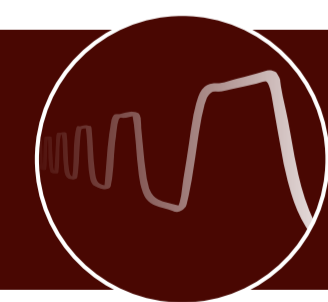
Applications
 Etch | Deposition | Medical
 RF Heating | Sterilisation | PECVD



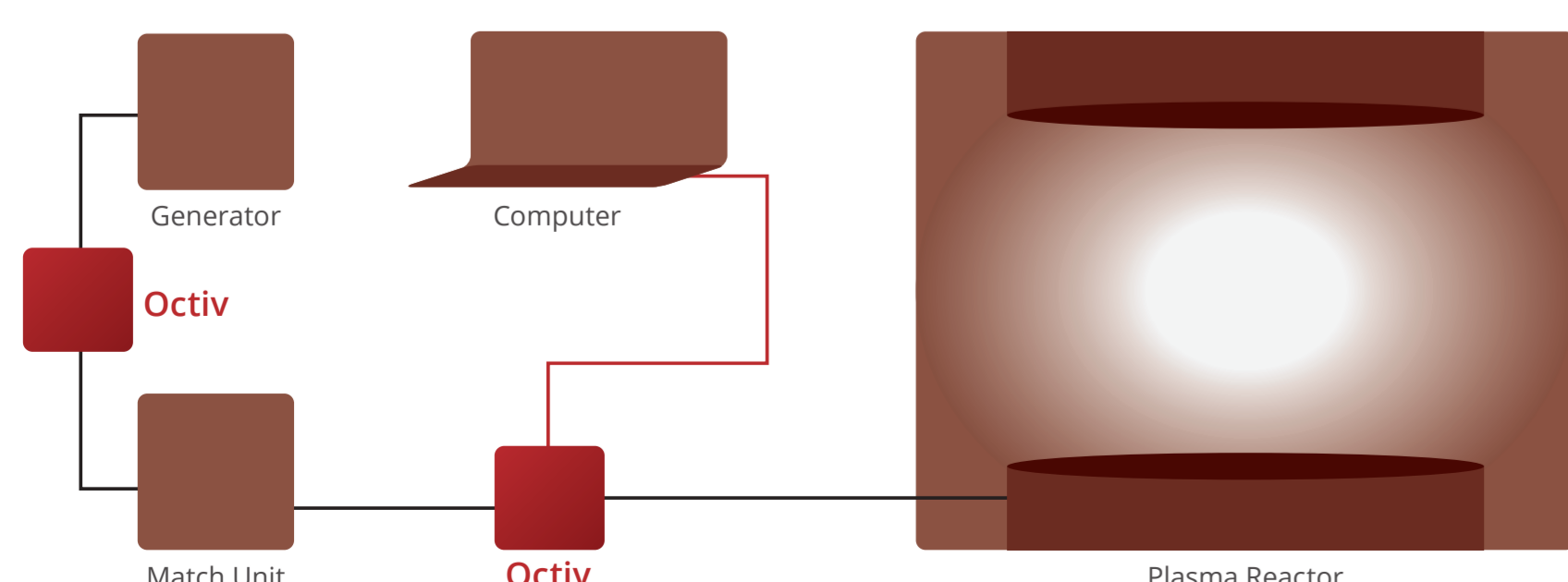
Moduli

RF Spectrometer
 Non-invasive Fault Detection
 RF Process Health Monitoring
 RF Event Detection

Applications
 Real-time monitoring
 End-pointing | Fault Detection



RF Plasma Power Measurement



Octiv Mono 2.0

Impedance RF Power Sensor
 Forward Power | Reflected Power
 Impedance
 Smith Chart

Applications
 Atmospheric | Dusty
 Etching | PECVD | Space
 Sputtering

Octiv Poly 2.0

VI Probe
 Voltage | Current | Phase
 Impedance | Harmonics
 Pulsed RF Compatible

Applications
 Atmospheric | Dusty
 Etching | PECVD | Space
 Sputtering

Octiv Suite 2.0

VI Probe
 Voltage | Current | Phase
 Impedance | Harmonics | Ion Flux
 Waveform Reconstruction

Applications
 Atmospheric | Dusty
 Etching | PECVD | Space
 Sputtering